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Attorney Docket P3P2000078US/2369NP

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Saundra D. Hunter
Saundra D. Hunter

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In Re Application of:

OKUDA, et al.

Confirmation: 1643

Serial No.: 10/018,708

Group Art Unit: 3723

Filed: April 15, 2002

Examiner: Wilson, Lee D.

For: TABLE OF WAFER POLISHING APPARATUS, METHOD FOR POLISHING SEMICONDUCTOR WAFER, AND METHOD FOR MANUFACTURING SEMICONDUCTOR WAFER

Commissioner for Patents
P.O. Box 1450
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RESTRICTION RESPONSE

Sir:

In response to the Office Action dated April 30, 2004, please enter the following remarks and amendments into the above-referenced application:

REMARKS

This is a Response to the Office Action dated April 30, 2004. Claims 1-37 are pending in the present application.

In the above-mentioned Office Action, the Examiner stated that claims 1-31 are subject to a restriction requirement under 35 U.S.C. § 121. In particular, the Examiner stated that: